

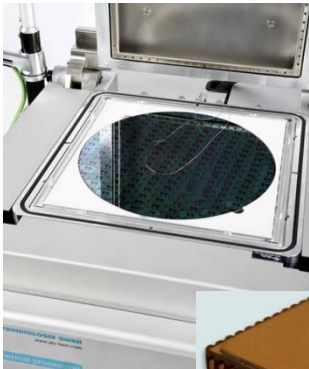


TECHNOLOGIE GMBH

thermal processing

SRO-71x

IR Vacuum Reflow/Brazing/RTA



Features

- Temperature: up to 1100°C
- Heated plates, up to 450 x 450 mm
- Fast heated plate ramping
 - Ramping up > 3.5°C/second
 - Ramping down > 2°C/second
- Rapid single wafer processing > 50°C/second
- 100 steps per program
- Oxygen < 0,1 ppm
- Hydrogen up to 100%
- 40 kHz/2,45 GHz plasma
- Formic acid activated nitrogen
- Ultimate Vacuum: ~ 7 x 10⁻⁷mbar
- High pressure atmosphere: up to 3 bar (abs)
- Flux less, with flux and solder paste
- Automation: cassette to cassette or in-line

General

The perfect soldering systems, solder reflow ovens (SRO) with rapid thermal annealing and brazing capability are IR lamp heated multi-purpose “cold wall” process ovens. The SRO is ideal for R&D, process development as well for low to high volume production.

Applications

Die attachment, IGBT/DBC, high vacuum encapsulation, MEMS package sealing, IR sensor/Crystal package sealing, wafer level packaging, thermo electric cooler/Peltier, low moisture package sealing, high power LED, laser bar, Getter activation, alloying, wafer bump/solder ball reflow, pin fin heat sink, backing, flip chip, 3 D-CSP, diffusion bonding, CPV, thermo compression bonding, pin fins, Hybrid assembly, MMIC die attachment, power modules, electric vehicle controls, power solar cells



Additional performance, developments, features and options:

Latest PLC architecture

MFC for precision gas flow control

Additional gas lines

CO atmosphere management

Oxygen and moisture monitoring

Controlled Formic Acid concentration

Pressure capability > 3 bar (abs)

- Steady state for higher process gas reactivity

- Steady state during cooling for lower flux pressure to minimize voids

- Pulsing pressure for better wetting

Direct substrate IR heating/N₂ cooling

- For pin fin heat sinks

- Warped heat sinks

- Faster processing

- Single wafer processing

Surface temperature sensing/touch TC

- When swapping pre populated heater plates/tooling/fixtures

- When swapping directly IR heated/N₂ cooled substrates/heat sinks

IR temperature measurement

Multiple monitoring TCs

100mm and more clearance above heated area

Spring pin array in chamber lid

- To flatten DBCs on heater plate without tooling

- For diffusion bonding

Low mass 3 pin wafer carriers

No warp heater plates

Fully and semi-automatic lid open/close

In-line integration/Cluster integration

SPC monitoring system

User administration

Integration into die bonders

Activated hydrogen/gas pre-heating

Ultra sonic/Vibration assisted reflow soldering

Nitrogen saving by recycled cooling gas

Water cooled fume traps

Microscope mount on swivel arm

Laptop shelf on swivel arm

Audible and visible status indication/light tree

IR lamp array in chamber lid/top side heater

- For much faster ramping

- For uniform heating of tall substrates/fixtures

Electrical and mechanical feed through

Lift pins

Closed-loop water chiller/heater

NRTL, SEMI or other standards

Bar code reader

Custom tailored tooling/fixtures with spring clamps

Spring clamps on heater plate

- For keeping parts in place

- For diffusion bonding

Thermo compression bonding

Process development



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